### PDF/SOLUTIONS"

#### 2023 PDF Users Conference:

AI for tomorrow's manufacturing

& R&D



Location:

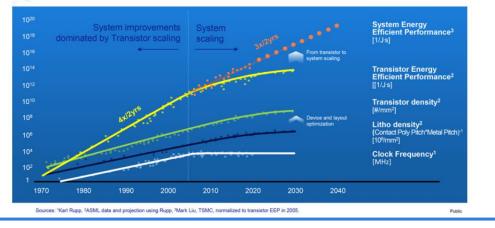
Santa Clara Marriott - 2700 Mission College Boulevard Santa Clara, California 95054 USA

### **Solutions for Fabs and IDMs**

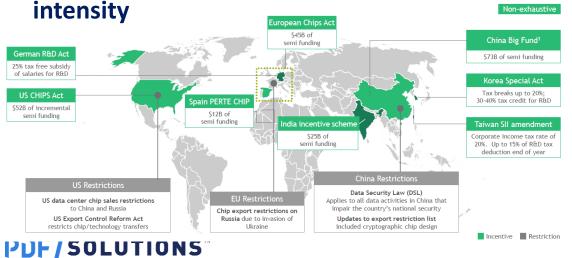
24<sup>th</sup> October 2023

### We are witnessing important shifts in the industry

### Scale drivers shifting from litho to 3D chips and advanced packages



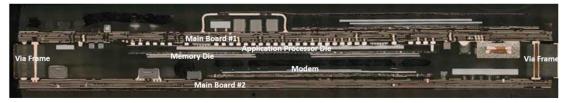
### Capacity investments shifting in location and



More complex and "More than Moore" devices require advanced characterization capabilities



### SiP changing test and assembly landscape w/ use of characterized KGD from variety of suppliers



iPhone X mainboard (SYSTEMPlus Consulting)

#### © 2023 PDF Solutions, Inc. 2

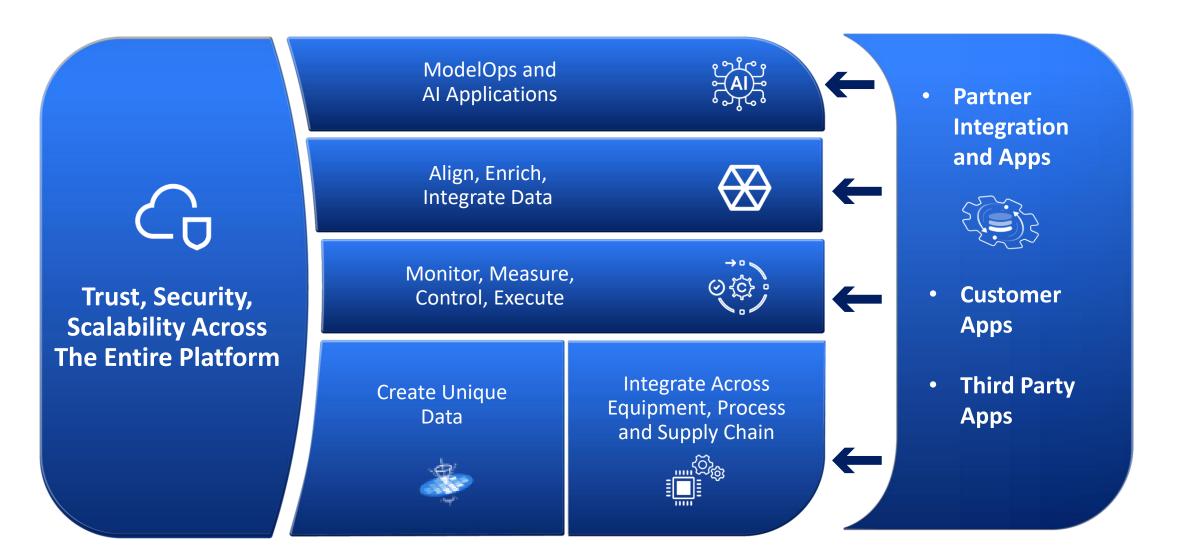
### **Observed Best Practices for Design Wins for Fabs and IDMs**



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\*Shared between Tech Dev and Manufacturing \*\* Shared between Customer Eng. and Tech Dev

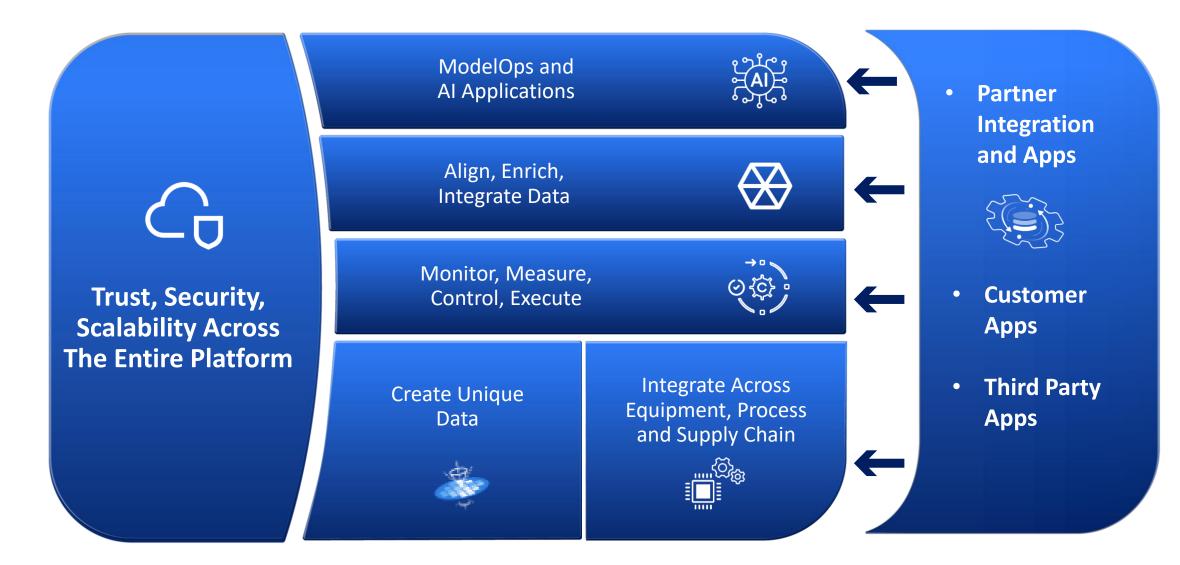
### PDF end to end platform for semiconductor analytics



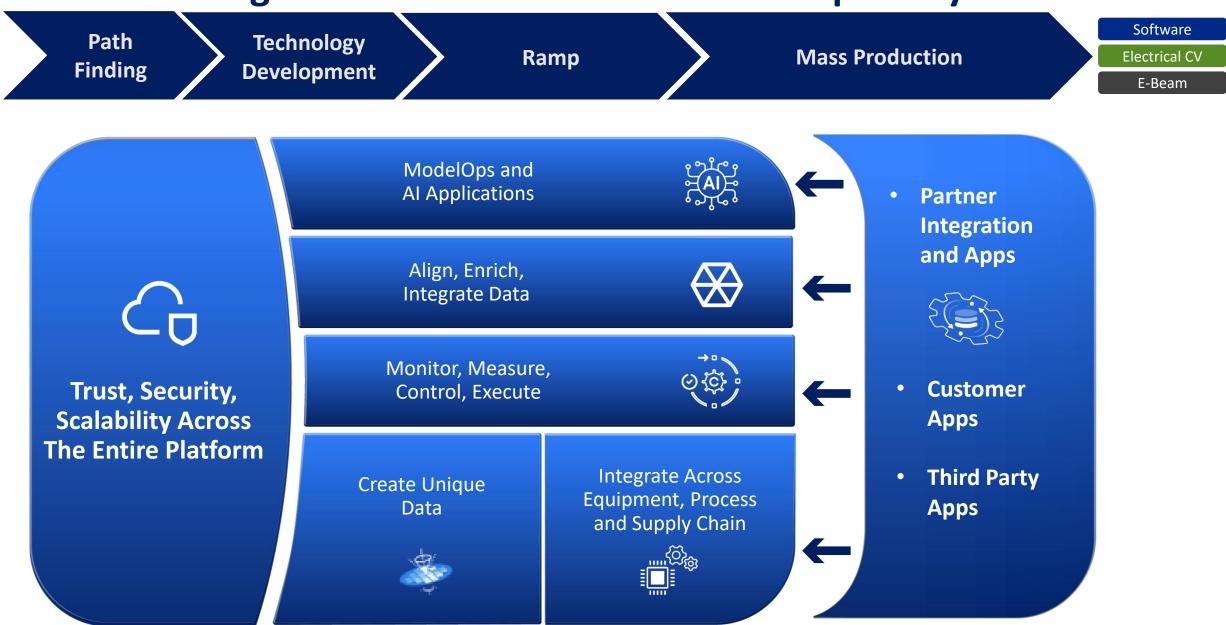
Fully integrated solution to accelerate production ramp, improve overall yield, quality, and efficiency for Semiconductors PDF/SOLUTIONS<sup>™</sup> © 2023 PDF Solutions, Inc. 4

### **Differentiated data on PDF's platform**





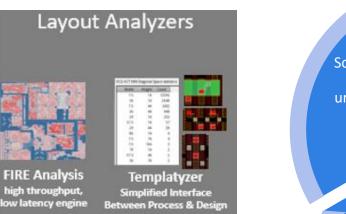
### **PDF offerings: Lab to Fab characterization capability**

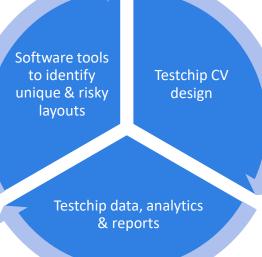




### Increased Focus on Process-Design-Systems Interaction

### Capabilities that support and reinforce each other



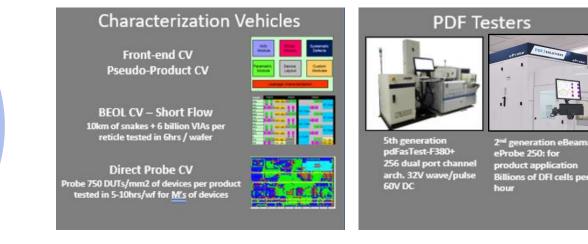


#### Templatyzer<sup>™</sup> std cell library analysis & golden cell generation

- DFM/IP Hardening by reducing use of unique or risky layouts
- DMCO: design for yield, variability to improve manufacturability

#### **FIRE™ full chip layout analysis**

- Statistics on the use of risky layout features and neighborhoods
- Yield entitlement calculation
- Output can be used to feed targeted test chips and inspection



**DPCV:** Direct Probing Characterization Vehicle (utilizes lower metal layers for option masks to measures tens of thousands of transistors in actual product layout)

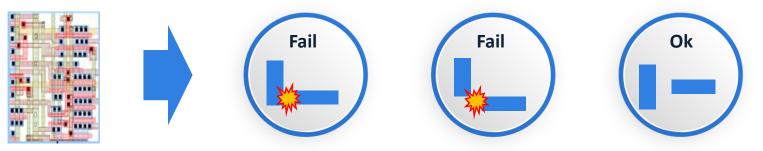
#### **Characterization suite**

- Different types of structures at different stages:
  - Definition: Early patterning constructs
  - Development: Pseudo-product layouts created from std cells
  - Early ramp: Actual product layouts
- Statistically valid sampling
- Transistor device selection based on FIRE layout extractions
- Unique tester capabilities
- Extensive analytics and reports



### **Exensio FIRE Software: Fuzzy Pattern Al**

A given systematic fail mode usually comes from, not one, but a "family" of layout configurations. Traditional rule-based approach is insufficient for the evolving complexity of product design at advanced nodes



Using fuzzy pattern image classification algorithms, PDF's FIRE software automatically groups all similar pattern into a "pattern family"



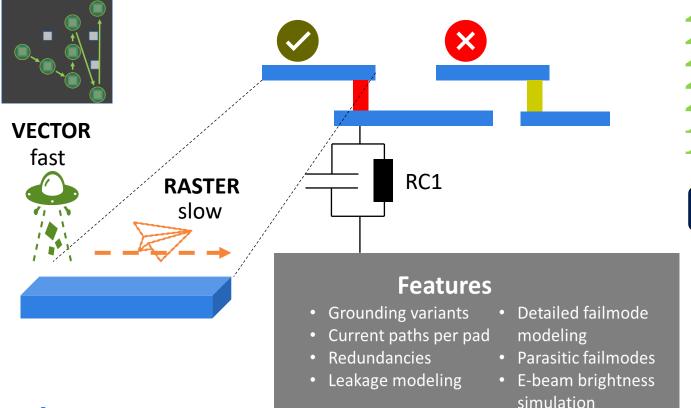


"How to Classify Photos of Dogs and Cats (with 97% accuracy)" -- machinelearningmastery.com

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### **Exensio FIRE Drives More Efficient Inline eBeam Inspect**

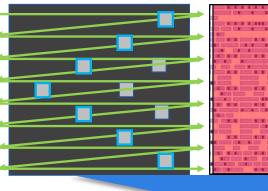
FIRE AI algorithm summarizes design characteristics and enables selection of scan points to take advantage of HW vector scan capability



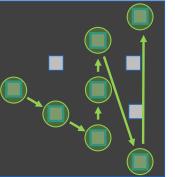
**PDF**/SOLUTIONS<sup>T</sup>

 Design Aware Inspection: eProbe knows precise pad type and location targeted IN REAL TIME for 10-100X efficiency gains

#### **Conventional ebeam Inspection**



#### eProbe Inspection



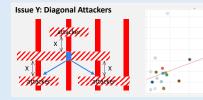
Continuous Stage Motion

9

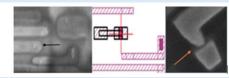


### **PDF DirectScan System Overview**

**1. Vulnerable Pattern** Library Systematic Yield Gap Analysis & Volume Diagnostics



#### **PFA** information



DFM

Inline Knowledge information

Test Structure Data

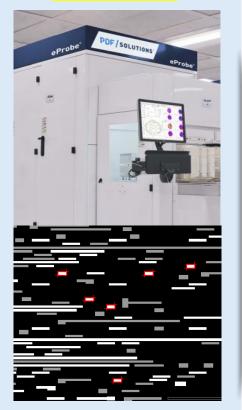


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**2.** Fire<sup>™</sup> Product Layout **Scan For Related Patterns** 

nage	liblmage	match	count
e-		0.099	3132
Ъ		0.095	288
ø	6	0.071	1539
-		0.070	342
1		0.070	222
		0.069	214
		0.068	456

#### **3. DirectScan product** wafer at layer with eProbe<sup>®</sup> 350



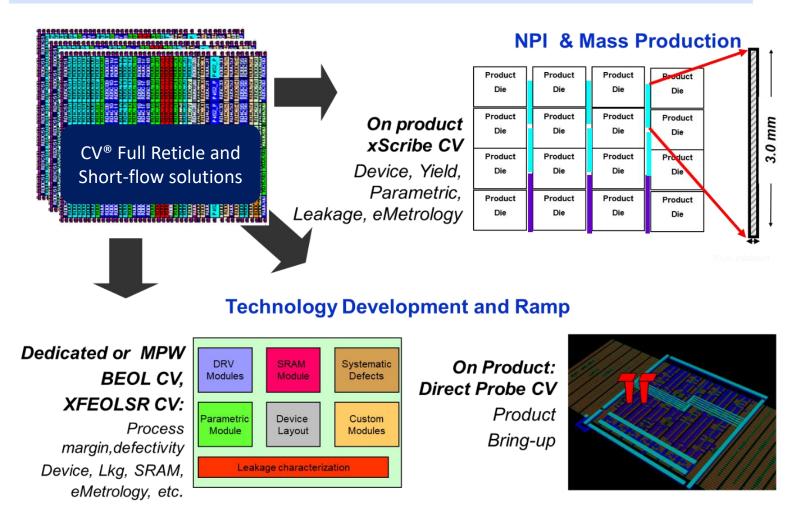
Unique Vector Scan performs Billions of measurements/wafer

Leak	age Bins >1nA (fail	150	Leakag	e Bina >10n	A (fairs)	> TuA	+ 100xA	= 10sA	a tak
ren l		6.38							0
	8.28			0.07		and a	(10)	-	
ne -	0.00			4.8			001		ō.
Fast							());	100:1	
Fam 0.03			1.02				0		Ö
			0.81				0		
7M7 4.54			0.01				-		
			6.41				0		
2365 0.01			1.00				000	0.11	
1970 0.00			0.08				0	-	
FMES 0.00			1.00			-	and a	-	

- Quantify yield impact in PPB stats  $\geq$
- Analyze key fail modes across full  $\geq$ product layout
- Characterize product pattern  $\geq$ neighborhood dependence for each fail mode
- Apply in TD and ramp for early  $\geq$ learning & characterization
- Apply in production for required  $\geq$ statistically significant monitoring and resolution
- Apply in process splits for  $\geq$ accelerated learning cycles

### **PDF Characterization Vehicle® Test Chips**

### Area efficient and fast-testable Test Chip solutions



PDF Characterization Vehicle® test chip = CV® test chip

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#### Characterization infrastructure for data collection

#### Inline & End of Line: CV Infrastructure

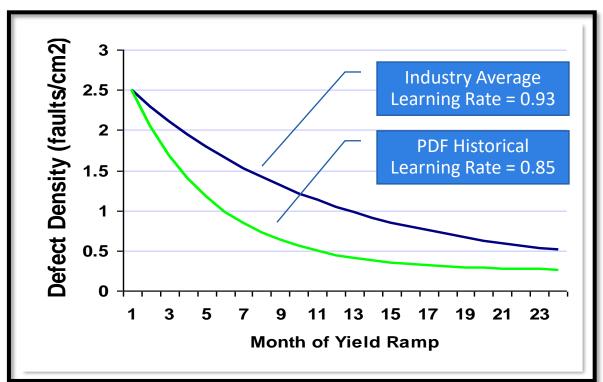


 Latest generation is >1000x faster vs. conventional architectures

 Includes parallel capacitance, parallel leakage, and pulsed memory test capability



### **Solutions Impact on Technology and Production Ramp**

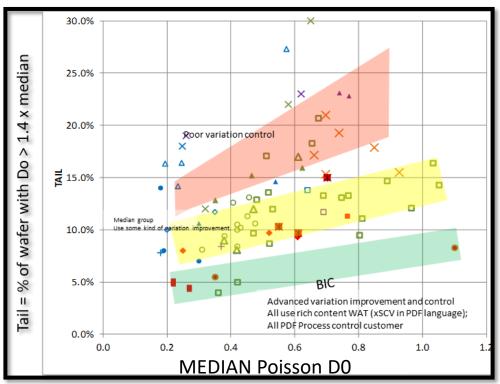


#### Learning Rate: D0 fraction reduced per month

- Benchmarked LR across nodes, products for 20 years
- Indicator of technology ramp speed and product readiness
- PDF's claim to fame is 2X reduction in time to ramp

#### Faster time to market, shorter time to volume:

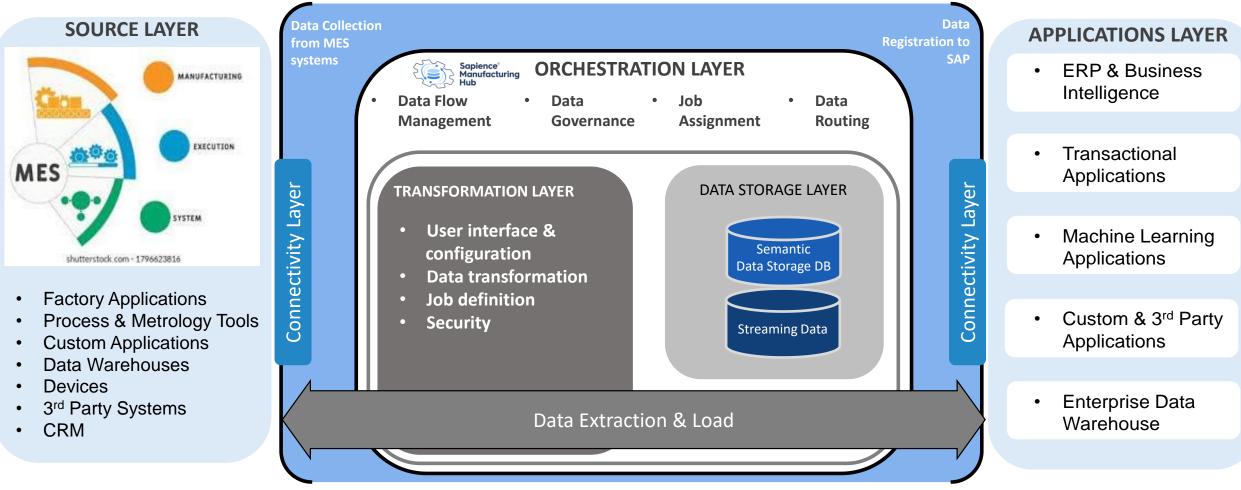
- Significant saving in engineering resources including wafers
- Increased profitability and ASP



- PDF has brought Tail levels to BIC concurrently with Technology Ramps across nodes and product mixes
  - Additional gain of \$40-50M/Q realized for 40KWSPM fabs
- Variability reduction results in
  - Lower Tail to ~ 4% (BIC) from 10% would gain 5% more good dies per wafer for 1 cm2 chip
  - Reduce rework rates and excursions

### **Sapience Manufacturing HUB Connecting the Siloes**



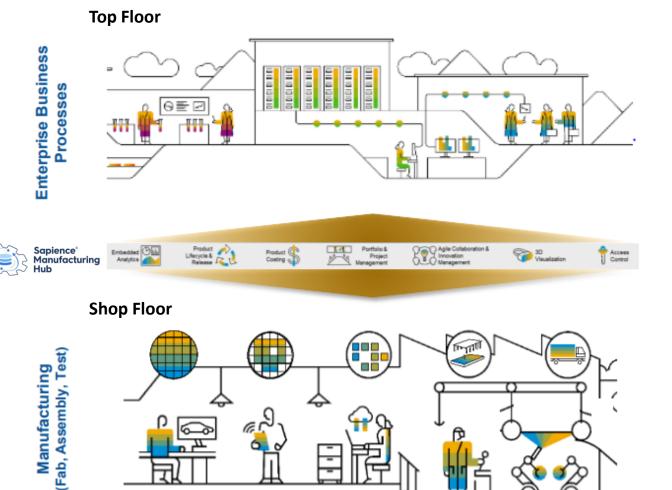


- The "Sapience Manufacturing HUB" is an Enterprise Application Integration (EAI) platform
- Provides the generic ability to connect to any MES, factory data system, device or tool regardless of location and move data between systems and platforms



### SAP + PDF Solutions – The Big Picture for Semiconductor Manufacturing

Seamless Business Process Integration to Engineering and Manufacturing Context and Data



### 1

2

A common logical model for Product / Assets supporting next generation E2E scenarios



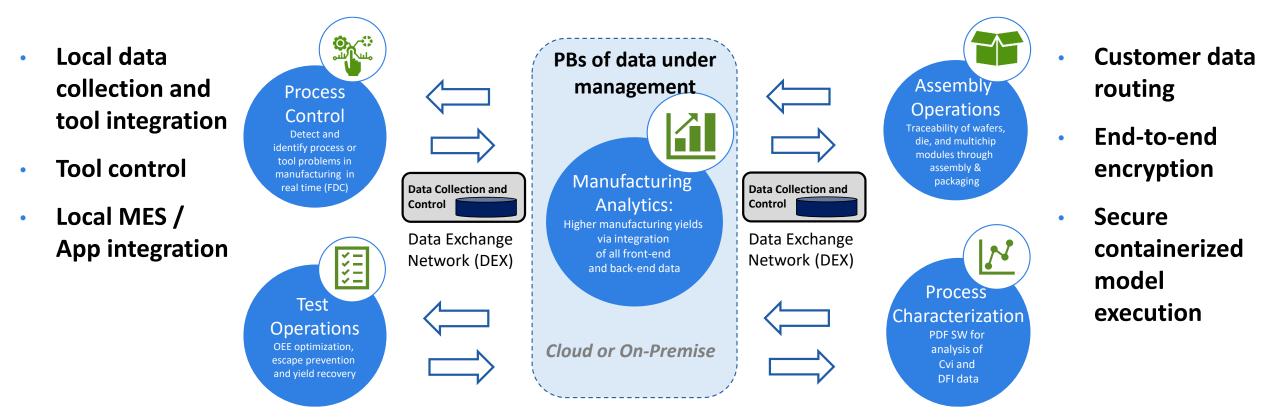
Semantic data model for standard pre-packaged content ready for consumption

Derive business, product, and service insights from manufacturing

#### **Opportunity**

- Simplification
  - Business Processes, Information Systems...
- Closed-loop business processes
- Greater visibility across supply chain
- Improved throughput, yield, test efficiency, asset management, factory planning, NPI, TTM...

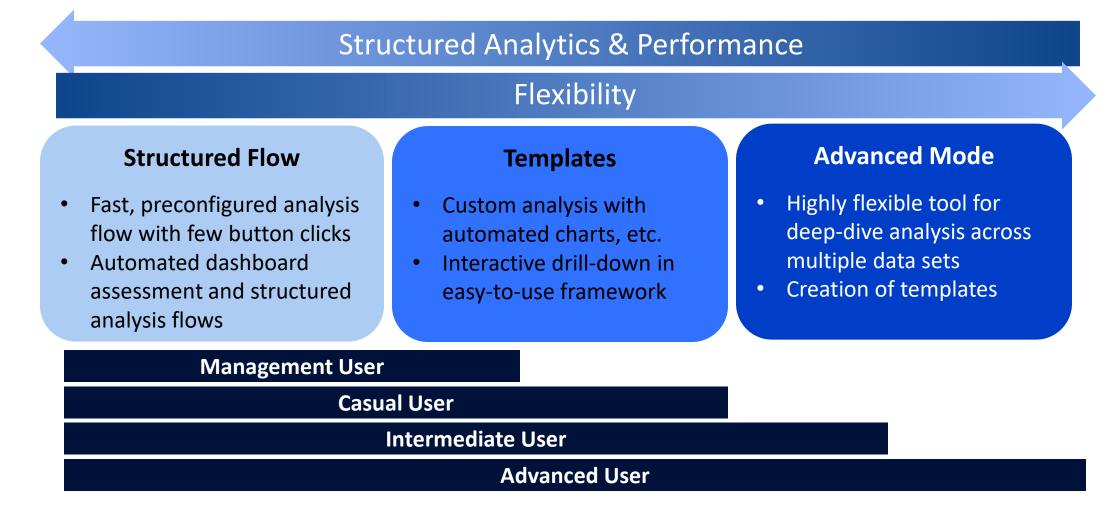
### Exensio Advanced Analytics, Data Quality & Edge Execution



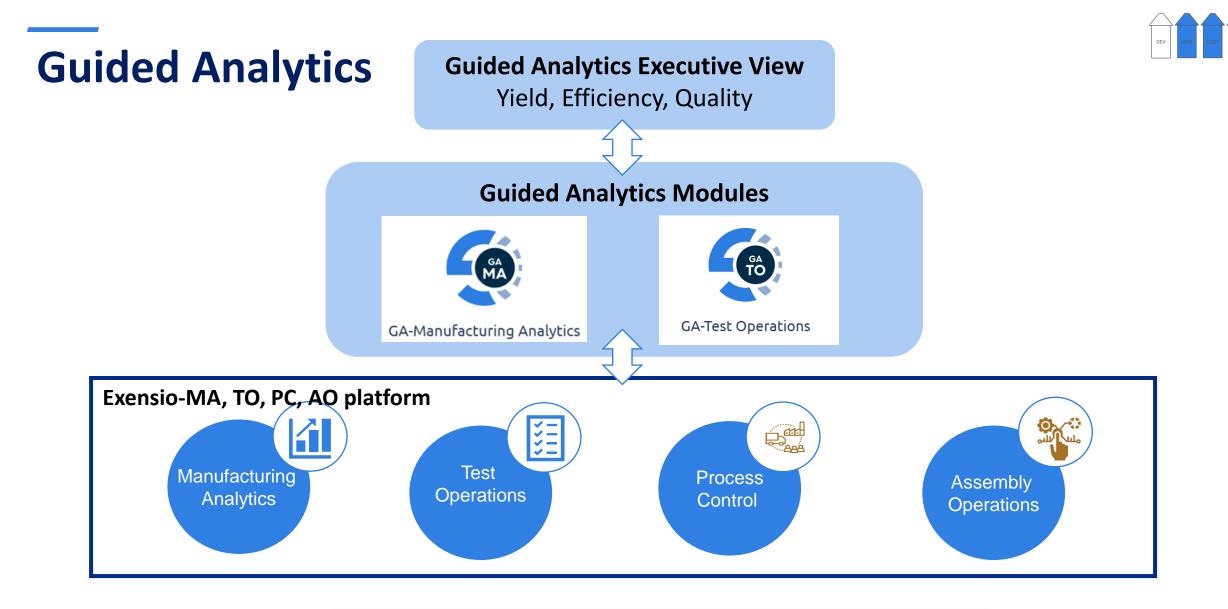
### Scalable and fast loading with built in redundancy



### **Guided Analytics:** Wide Range of Use Modes



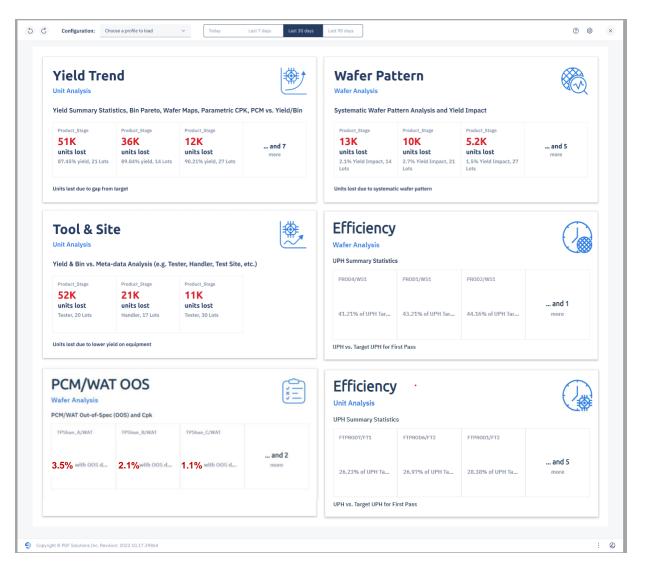
#### **Guided Analytics enables fast time to meaningful results**



Easy to learn, high efficiency analysis

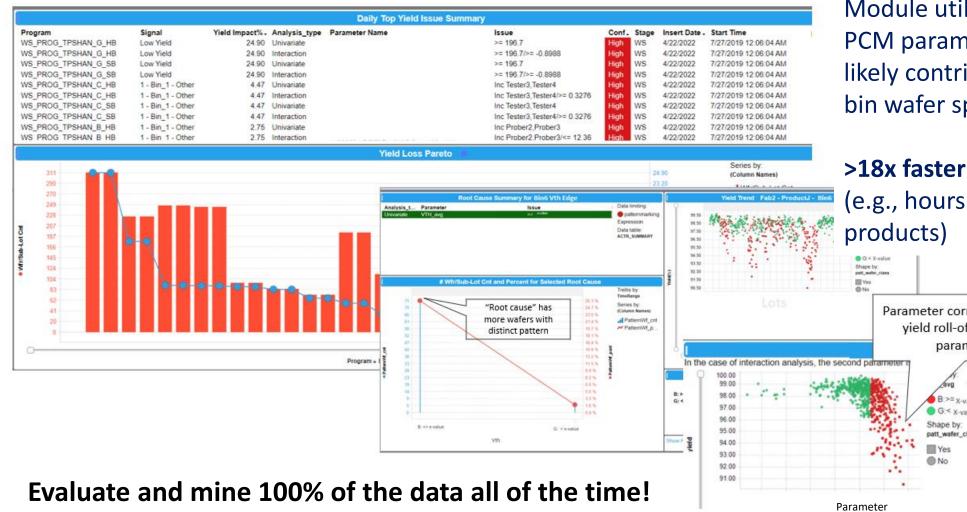
### **Guided Analytics:** Automated Prioritization of Yield Issues

- High-level dashboard provides assessment across multiple products
- Preconfigured analysis framework guides the user through an issue-based analysis path
  - Yield trends and gaps to target
  - Wafer-level systematic signatures
  - Lower yielding test cell equipment
  - PCM/WAT OOS wafers
  - Throughput lower than target
  - AI/ML driven diagnosis for excursion, low yields and wafer-level patterns (add-on)
- **Effective tool for high number of products**
- Profiles for user-specific configurations stored in database



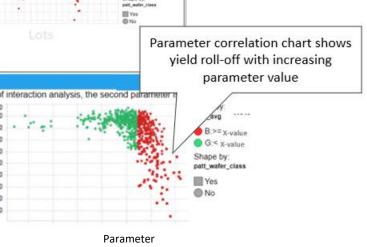
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### GA Accelerated Root Cause Diagnosis Powered by AI/ML

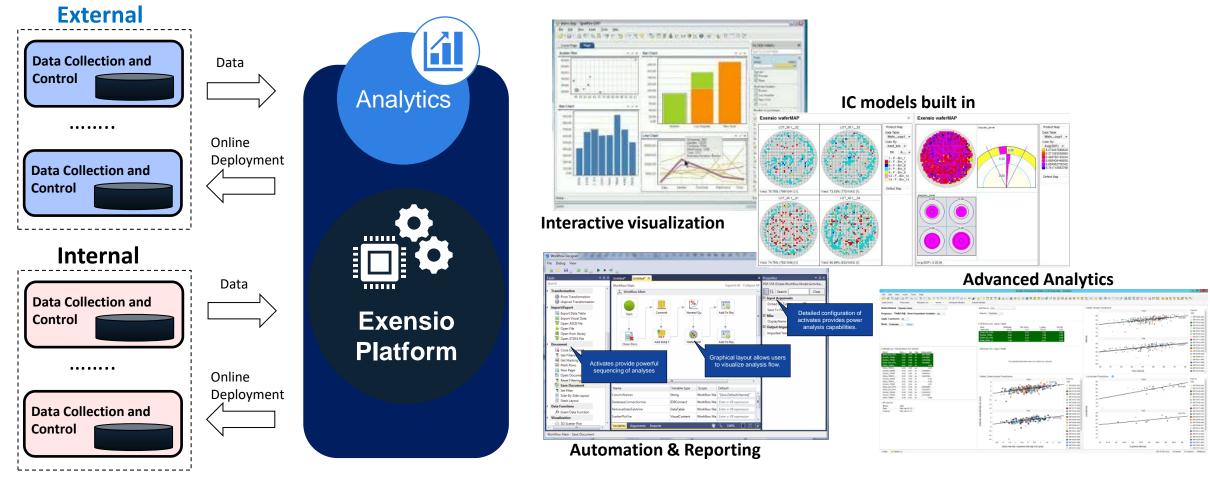


Module utilizing AI/ML identifies PCM parameters and test equipment likely contributing to yield loss and bin wafer spatial patterns

### >18x faster than manual analysis (e.g., hours vs. weeks for 2000



### Manufacturing Analytics: Integrating Frontend & Backend Data



Provides powerful signature analysis and diagnostics

Industry leading application for high volume data analytics & visualization

**New Product Introduction & Characterization Feature Matrix** 

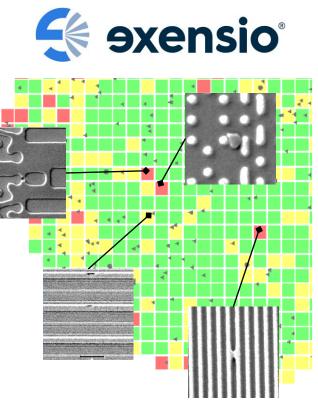
Capability	Exensio Manufacturing Analytics	Partnership	75.03% 7.34% 6.79%	Cum. Fail % 75.03% 82.37% 89.16%	Cum. Fail Pareto	350 - 300 - 250 -	c	olor by: CalcLot Comp Ref
Test Program Validation & Optimization			4.64% 1.35%	93.81% 95.16%		200 -		
Test Coverage (Never failing / Redundant tests)	$\checkmark$		1.15% 0.79%	96.31% 97.10%	1	150 -		
Limits Analysis			0.75%	97.86%	i	100 -		
Specification, Guard band Limit Setting			0.48%	98.33% 98.69%		50 -		
	V		0.20%	98.89%	i		0.40 0.42 0.44 0.46 0.48 0.48 0.50 0.50	
Product Characterization			0.16%	99.05%	1		S VTN_20X20 (20 bins)	
Wide / Sweep Data Handling	$\checkmark$		0.16% I Normal Quantile Pl	99.21%		I Waf	er Map	-
CP / CPK Analysis, VDD / Temp Char Analysis	$\checkmark$		3.5		Color by: Lot + + +		LOT_38.1 LOT_38.4 Product Map	
Fab / Supplier Matching & Qualification	$\checkmark$		0.5		LOT_38.1 LOT_38.4 LOT_39.1		Coordy & Coo	6148e-7
Reporting / Templates / Release to Production	$\checkmark$		-0.5 -			1.21e-7	(1)         1.19e-7 [1]         1.10652e-7 - 1.16           LOT_39.1         LOT_181.1         1.21661e-7 - 1.27	6157e-7 1661e-7
Design / Layout Sensitivities to Process			-2.5	1 miles			Defect Map	
WS / FT to WAT: Die Level Process Sensitivity	$\checkmark$		9.4E-08	1.04E-07	1.14E-07 1.24E-07	1.14e-7	1.13e-7 [1]	
On Chip Agents	$\checkmark$	$\checkmark$	Box Plot		• Temp ▼ + ▼	l Bar	Chart	Temp
Fault Diagnostics		$\checkmark$	8.80000 8.70000 8.60000 8.50000 8.40000		-40c 0c 125c 25c 70c			<ul> <li>-40c</li> <li>0c</li> <li>125c</li> <li>25c</li> <li>70c</li> </ul>
IDM / FAB			8.30000 8.20000 23 8.10000 8.00000			2J		
Linkage with process data (fab, defect, fdc, etc)	$\checkmark$		53 7.8000 7.70000 7.60000 7.50000			11 25 11		
Split Lot Analysis	$\checkmark$		-40c Count 128 Median 8.05 Outliers 3	0c 125c 52 28 8.045 8.1 3 0 Temp ▼	250         70c         Alpha level = 0.05           82         80         Roth MSE = 0.246           8.05         8.07         sqrt(2)q* = 3.877           2         0         +	0. 0.	750 750 770 780 750 800 810 820 830 840 850 850 850 800	.0

### **Exensio Defect Management System**

### WHAT SETS US APART

- #1 end-to-end Defect and Yield Management across the entire supply chain
- Used by 9 large fabs and IDMs in the US, Asia and EU
- Compliant with all standard DMS requirements
- Highly scalable deployments on-prem and in the cloud
- The first to implement device traceability to enable tracing electrical fails to inline defects
- Fully independent: equipment agnostic with support of all fab data types

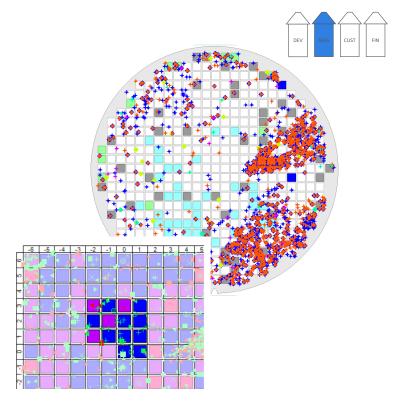


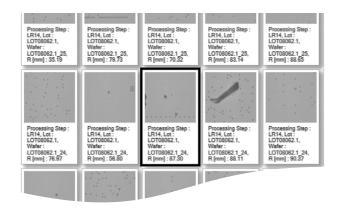




### **DMS: Solutions Overview**

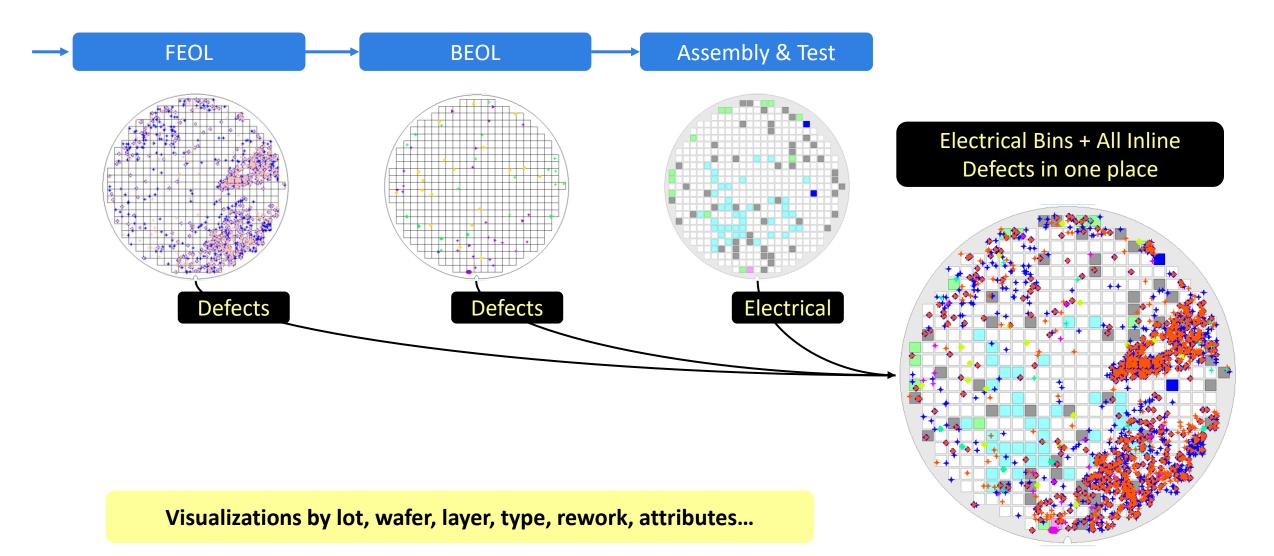
- Defect Map Defect data storage and analysis with mapping capability and alignment with other data types
- Defect Map Class Classification of defects to group similar defects by type for Kill Rate and Capture Rate summaries
- Defect Map Gallery Gallery of inspection and review images linked to inspection site (thumbnail gallery)

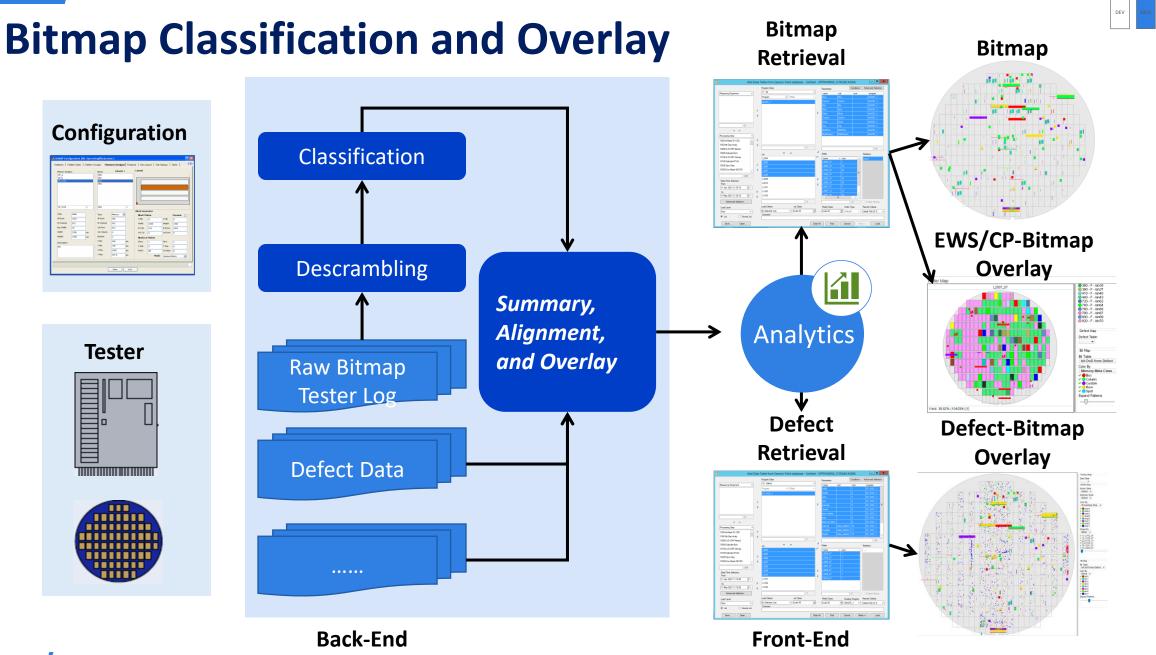




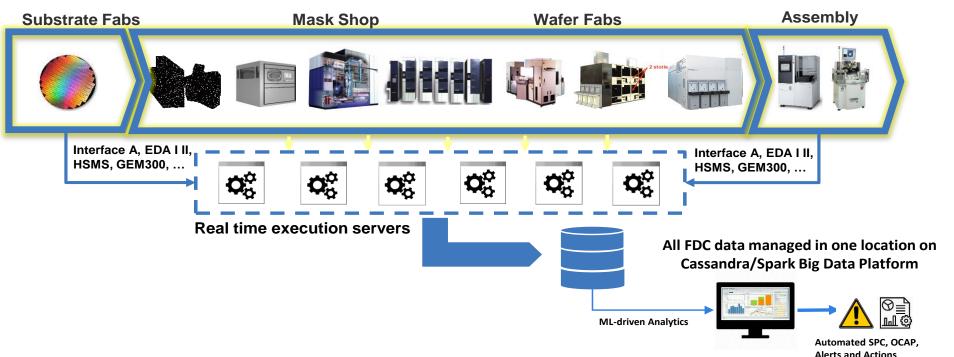
### **DMS: Defect-Bin Overlays**







### **Process Control: Advanced FDC for Manufacturing Tools**



#### An Industry leader for FDC control solutions

Over 40,000 process tools under PDF control

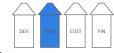
LUTIONS

- Online control & offline analytics (real-time & summary FDC)
- Advanced analysis, AI, ML, SPC, OCAP, dashboards, automation

FDC based decisions and process control at tool and factory levels:

- Reduced excursions & tool induced process variability
- Reduced maintenance resource costs and requirements
- Tighter yield and parametric distributions

### Identify, diagnose, & prevent tool problems



### **Exensio Process Control Applications for Fabs and IDMs**

#### **1.** Superior data acquisition quality :

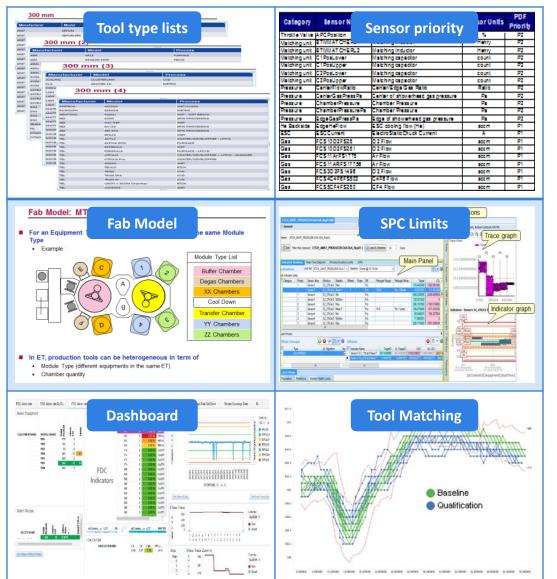
- a. 20+ years experience integrating 200 and 300mm toolset cover almost all of tool types
- b. Extra sensor compatibility and Interface-A / EDA compatibility
- c. Sensor audit based on PDF knowledge base derived from worldwide YAFDC experience

#### 2. On-line control:

- a. Control limits & OCAP on FDC Indicators with wafer level alarm & interdiction
- b. Multi-level limits, Multi-auto limits algorithms, WECO rules and Offsets
- c. Fab Model provides 10+ times of efficiency improvement

#### 3. Auto reporting and Dashboard:

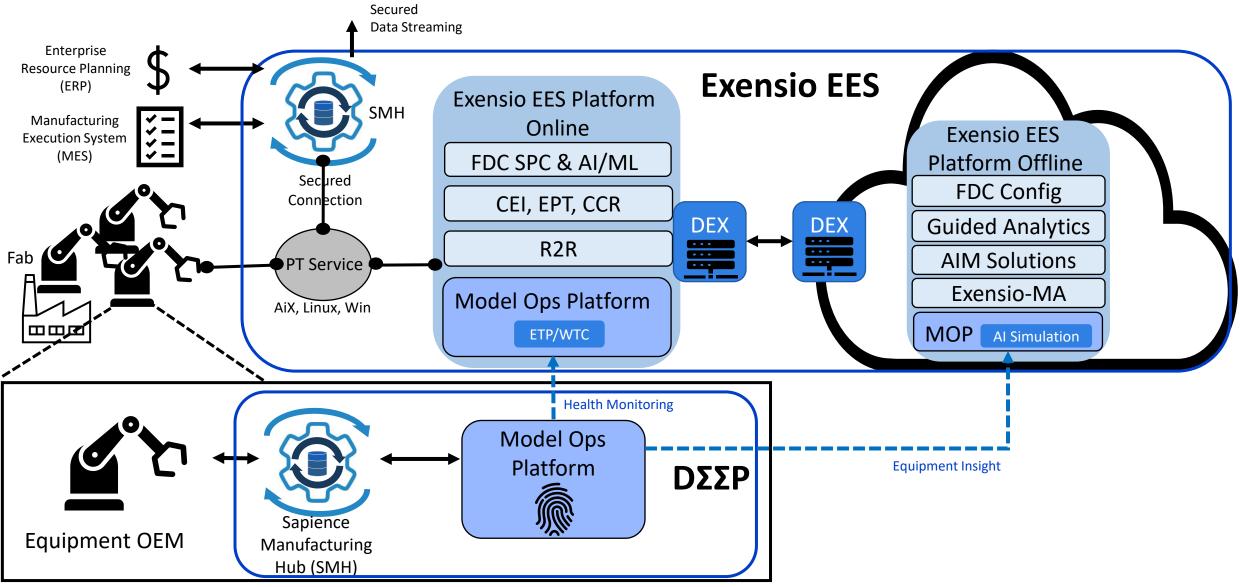
- a. Dynamic statistical reports enable flexible management of global FDC status
- b. Excursion diagnostics drill down to trace level effectively reduce FDC alarms
- c. Configurable chamber matching auto-reports & analysis templates for auto-diagnostics



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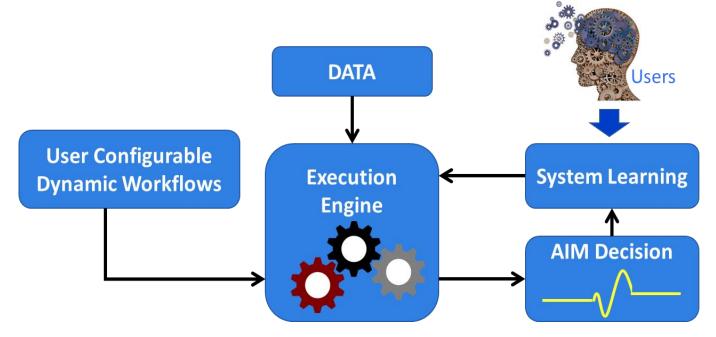
### **Exensio Equipment Engineering System Platform**





### **AIM – Advanced Insights for Manufacturing**

Big Data Infrastructure to connect and relate ALL of the necessary data types & built-in understanding of interactions between design – fabrication – electrical



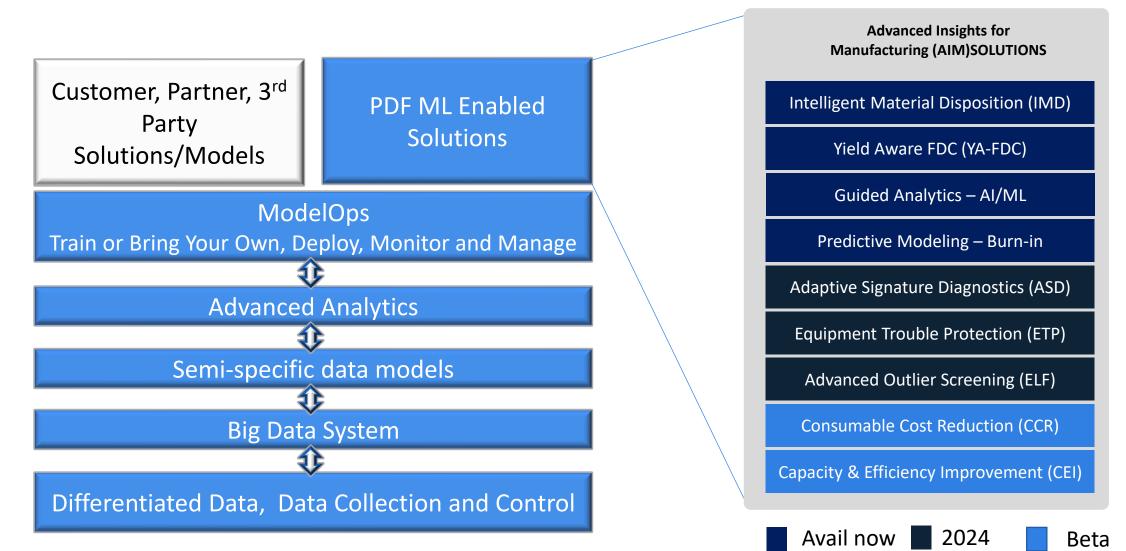
Application of these foundational elements to provide solutions to the specific needs of the I.C. manufacturer

## Hardware Software

- Performance to explore, visualize, and analyze the varied types of data and apply AI & Machine Learning
- Scale to handle the rapidly increasing range of data types, volume, variety, and velocity



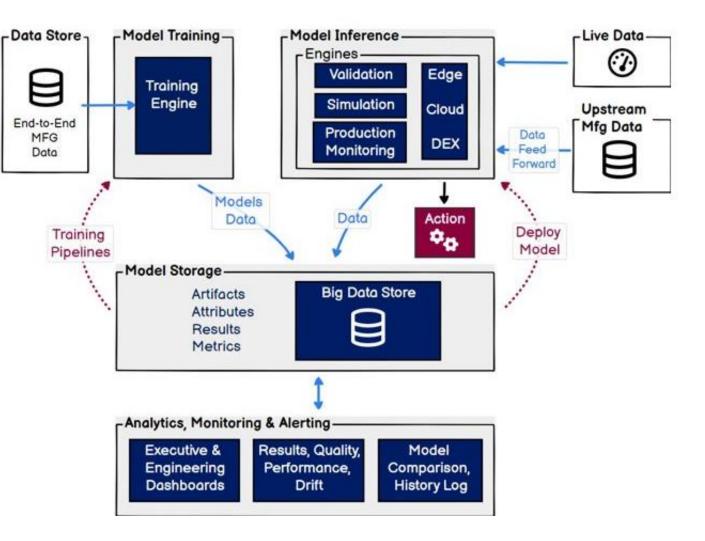
### **ModelOps and AIM Solutions**



### PDF Platform Model Ops Enables Scaling & Performance

large numbers of models, big data volumes, real-time inference

- Integrated with the Exensio platform to leverage semi data access, analytics and control
- Central Model Storage System
- Dynamically Scalable Big Data model training infrastructure
- Deploys to Cloud & real-time Edge
   Inference Engines
- Bring-your-own Algorithm / Model / Inference Engine





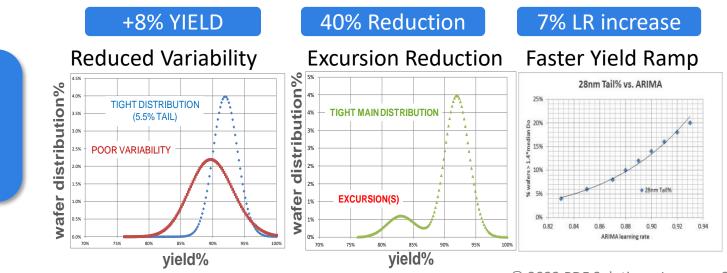
### **YA-FDC Yield Aware Fault Detection & Classification**

#### Combination of technology and services that utilizes Exensio's FDC & YMS 'big data' and applies AI/ML

- Implements better characterization of process variation
- Identifies equipment conditions and variability that influence functional and parametric yield & sets appropriate SPC limits through proprietary analysis and modeling techniques to identify critical parameters
- Automated analysis, dashboards, & reporting that drives fast improvement on yield variation & cost reduction

#### Includes AI and Machine learning such as

- Predictive models to for finer control including feed-forward and feed-back control options
- Predictive PM's to optimize tool availability
- Virtual Metrology driving adaptive sampling for inspection and metrology



#### • AI FDC Benefits Demonstrated

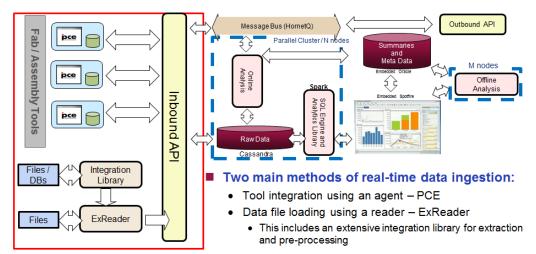
- 8% Yield Improvement
- 40% Excursion reduction
- 7% Faster Ramp of New Products

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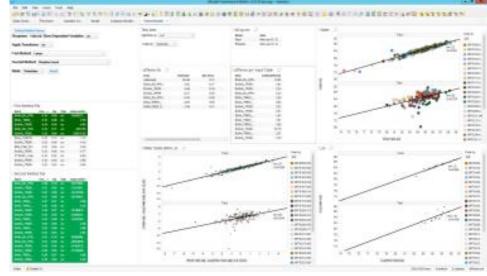


### Yield Aware FDC uses 'Big Data' and Machine Learning

- Yield Aware FDC is built-on a scalable 'Big Data' platform with superior performance vs. RDBS
- Yield Aware FDC control plans use feedback (correlations & modeling) to find the important signals to be tightly monitored & controlled
  - Response data (Metrology, NPW, Defect, PCM, Yield, Events)
  - Sensor, PM, and FDC event data
- Yield aware uses machine learning tools i.e. advanced MVA, virtual metrology, and predictive modeling to provide the insights needed for high quality & reliable parts manufacturing by improving tool/process control



#### Hybrid multi-variate model



#### Example: Linear + Random Forest (many other algorithms available)



### **YA-FDC Solution Examples**

#### **Fault Detection and Classification**

- Predict wafer failure at a process or test station using upstream tool sensor data
- Identify root cause of failures quickly by linking back to significant features

#### **Predictive Maintenance**

- Using tool sensor data, predict when a tool will go down or need maintenance
- Identify root cause of tool issues

#### Virtual Metrology / Virtual Sensing

- Predict Critical Dimensions (CD) for specific process steps using sensor and inline data
- Immediately identify excursions and extend consumable life

#### **Fab Predictive Model**

- Use data from throughout the fab to predict wafer disposition
- Use data from unit process operations to predict non-product (NPW) responses

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### **PDF Solutions Platform Capabilities for Fabs and IDMs**

Key functionality that enables customers to achieve high value results





### **AI Focused Roadmap of PDF's Advanced Solutions**

### PDF's vision and mission

 Vision: To be the world's leading data and analytics platform spanning the semiconductor and electronics ecosystems.

Mission: Provide innovative solutions to create, access, and organize data to enable analysis and control for semiconductor and electronics companies to achieve better time-to-market, yields, quality, and operational efficiencies.

### 2023 & 2024 roadmap focus

- Using AI to connect design and analytics together by developing unique data and apps, including with partners, for diagnostic (including DFI) and adaptive test
- Using AI to generate unique observations to characterize process & product, and feed into PDF's overall Exensio platform to help our customer to achieve better yield, quality, and operation efficiency.

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This presentation and discussions resulting from it may include future product features or fixes, or the expected timing of future releases. This information is intended only to highlight areas of possible future development and current prioritizations. Nothing in this presentation or the discussions stemming from it are a commitment to any future release, new product features or fixes, or the timing of any releases. Actual future releases may or may not include these product features or fixes, and changes to any roadmap or timeline are at the sole discretion of PDF Solutions, Inc. and may be made without any requirement for updating. For information on current prioritizations and intended future features or fixes, contact sales@pdf.com.

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